



PATENT APPLICATION

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q67319

Tsutomu SHOKI, et al.

Appln. No.: 09/987,990

Group Art Unit: 1756

Confirmation No.: 8044

Examiner: ROSASCO, STEPHEN D

Filed: November 16, 2001

For: SUBSTRATE WITH MULTILAYER FILM, REFLECTION TYPE MASK BLANK FOR EXPOSURE, REFLECTION TYPE MASK FOR EXPOSURE AND PRODUCTION METHOD THEREOF AS WELL AS PRODUCTION METHOD OF SEMICONDUCTOR DEVICE

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136

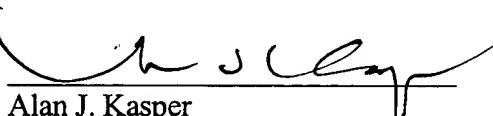
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.136, Applicant hereby petitions for an extension of time of one month(s), extending the time for responding to the Office Action of July 15, 2003 to November 15, 2003.

A check for the statutory fee of \$110.00 is attached. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,


Alan J. Kasper
Registration No. 25,426

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Date: November 14, 2003